Please add the following new claims:

8. (New) A micromechanical yaw rate sensor, comprising:

a substrate;

a bridge;

an anchoring device provided on the substrate and including two opposite bases that are connected fixedly with the substrate and that are connected with one another via the bridge;

a flexural spring device; and

an annular flywheel that is connected via the flexural spring device with the anchoring device such that an area of connection with the anchoring device is located essentially in a center of a ring of the flexural spring device, so that the annular flywheel is able to be displaced, elastically from a rest position, about an axis of rotation situated perpendicular to a surface of the substrate, and about at least one axis of rotation situated parallel to the surface of the substrate, wherein:

at least one V-shaped flexural spring of the flexural spring device is attached to each of opposite sides of the bridge in such a way that an apex is situated on the bridge and limbs of the bridge are spread towards the annular flywheel with an opening angle.

9. (New) The micromechanical yaw rate sensor according to claim 8, wherein:

the at least one V-shaped flexural spring includes a first V-shaped flexural spring and a second V-shaped flexural spring, and

the opening angle is equal for the first V-shaped flexural spring and the second V-shaped flexural spring.

10. (New) The micromechanical yaw rate sensor according to claim 9, wherein:

the first V-shaped flexural spring and the second V-shaped flexural spring are attached to the bridge such that the first V-shaped flexural spring and the second V-shaped flexural spring form an X shape.

11. (New) The micromechanical yaw rate sensor according to claim 10, wherein:

the opening angle is selected such that a natural frequency about the axis of rotation situated perpendicular to the surface of the substrate is smaller than each natural frequency about the axis of rotation situated parallel to the surface of the substrate.

12. (New) The micromechanical yaw rate sensor according to claim 8, wherein:

the two opposite bases are in the shape of a wedge and include two wedge tips, and

the bridge connects the two wedge tips with one another.

13. (New) The micromechanical yaw rate sensor according to claim 8, wherein:

the bridge is suspended freely over the substrate from the two opposite bases.

14. (New) The micromechanical yaw rate sensor according to claim 8, wherein:

the micromechanical yaw rate sensor can be manufactured using one of silicon surface micromechanical technology and another micromechanical technology.

Remarks

This Preliminary Amendment cancels original claims 1-7, without prejudice, in the underlying PCT Application No. PCT/DE00/02931. The Preliminary Amendment also adds new claims 8-14. The new claims conform the claims to U.S. Patent and Trademark Office rules and do not add new matter to the application.

In accordance with 37 C.F.R. § 1.121(b)(3), the Substitute Specification (including the Abstract, but without the claims) contains no new matter. The amendments reflected in the Substitute Specification (including Abstract) are to conform the Specification and Abstract to U.S. Patent and Trademark Office rules or to correct informalities. As required by 37 C.F.R. § 1.121(b)(3)(iii) and § 1.125(b)(2), a Marked Up Version Of The Substitute Specification comparing the Specification of record and the Substitute Specification also accompanies this Preliminary Amendment. Approval and entry of the Substitute Specification (including Abstract) are respectfully requested.